

FOREIGN PATENT DOCUMENTS

EXAM. INIT.	REF. DES.	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATE YES/NO
TT		1 319 388	06/06/73	Great Britain	H01L	9/00	Yes
TT		0 117 045	08/29/84	EPA	H01L	45/00	Yes
TT		JP 60109266	06/14/85	Japan	H01L	27/10	Yes

OTHER ART (Author, Title, Journal, Volume, Pertinent Pages, & Date)

TT		Kim and Kim, "Effects of High-Current Pulses on Polycrystalline Silicon Diode with n-type Region Heavily Doped with Both Boron and Phosphorus," <i>J. Appl. Phys.</i> , 53(7):5359-5360, 1982.
TT		Neale and Aseltine, "The Application of Amorphous Materials to Computer Memories," <i>IEEE</i> , 20(2):195-205, 1973.
TT		Pein and Plummer, "Performance of the 3-D Sidewall Flash EPROM Cell," <i>IEEE</i> , 11-14, 1993.
TT		Post and Ashburn, "Investigation of Boron Diffusion in Polysilicon and its Application to the Design of p-n-p Polysilicon Emitter Bipolar Transistors with Shallow Emitter Junctions," <i>IEEE</i> , 38(11):2442-2451, 1991.
TT		Post <i>et al.</i> , "Polysilicon Emitters for Bipolar Transistors: A Review and Re-Evaluation of Theory and Experiment," <i>IEEE</i> , 39(7):1717-1731, 1992.
TT		Post and Ashburn, "The Use of an Interface Anneal to Control the Base Current and Emitter Resistance of p-n-p Polysilicon Emitter Bipolar Transistors," <i>IEEE</i> , 13(8):408-410, 1992.
TT		Rose <i>et al.</i> , "Amorphous Silicon Analogue Memory Devices," <i>J. Non-Crystalline Solids</i> , 115:168-170, 1989.
TT		Schaber <i>et al.</i> , "Laser Annealing Study of the Grain Size Effect in Polycrystalline Silicon Schottky Diodes," <i>J. Appl. Phys.</i> , 53(12):8827-8834, 1982.
TT		Yamamoto <i>et al.</i> , "The I-V Characteristics of Polycrystalline Silicon Diodes and the Energy Distribution of Traps in Grain Boundaries," <i>Electronics and Communications in Japan</i> , Part 2, 75(7):51-58, 1992.
TT		Yeh <i>et al.</i> , "Investigation of Thermal Coefficient for Polycrystalline Silicon Thermal Sensor Diode," <i>Jpn. J. Appl. Phys.</i> , 31(Part 1, No. 2A):151-155, 1992.
TT		Oakley <i>et al.</i> , "Pillars - The Way to Two Micron Pitch Multilevel Metallisation," <i>IEEE</i> , 23-29, 1984.
TT		Prince, "Semiconductor Memories," A Handbook of Design, Manufacture, and Application, 2 nd Ed., pgs. 118-123.

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DATE CONSIDERED

11-08-01

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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